

FORM PTO-1449 • U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  INFORMATION DISCLOSURE STATEMENT BY APPLICANT  (USE SEVERAL SHEETS IF NECESSARY)	ATTY. DOCKET NO. ASMMC.045AUS	APPLICATION NO. 10/696,244
	APPLICANT Raaijmakers et al.	
	FILING DATE October 28, 2003	GROUP <del>2812</del> 2823

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	PAGE	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
<i>Lee</i>	1	5,913,144	06/15/99	Nguyen et al.			
	2	5,918,150	06/29/99	Nguyen et al.			
	3	6,348,402	02/19/02	Kawanoue et al.			
	4	6,153,515	11/28/00	Murakami et al.			
	5	6,391,785B1	05/21/02	Satta et al.			
<i>Lee</i>	6	2002/0004293 A1	01/10/02	Soininen et al.			

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)	
<i>Lee</i>	7	Chen et al., "The Effect of Surface Oxides on Cu/Ta Interfacial Interactions" Mat. Res. Soc. Symp. Proc., Vol. 564, 1999 pp. 287-292

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051204

EXAMINER	<i>Shan Ming Lee</i>	DATE CONSIDERED	<i>2/23/05</i>
*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.			

*paper no. 051804*